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THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Kiyoshi IRINO et al.**

Group Art Unit: **2815**

Serial No.: **09/428,052**

Examiner: **Jose R. Diaz**

Filed: **October 27, 1999**

Confirmation No.: **4139**

For: **METHOD OF FABRICATING A SEMICONDUCTOR DEVICE
CONTAINING NITROGEN IN A GATE-OXIDE FILM**

Attorney Docket Number: **970901A**

Customer Number: **38834**

AMENDMENT AFTER FINAL REJECTION

Mail Stop AF

Commissioner for Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

December 9, 2004

Sir:

This paper is filed in response to the Office Action dated September 9, 2004.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 6 of this paper.